

**PATENT**

OK TO ENTER: (US/104/09/2008)  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:** Luo et al.

**Serial No.:** 10/826,985

**Filed:** April 19, 2004

**For:** METHODS FOR FORMING PROTECTIVE  
LAYERS ON SEMICONDUCTOR DEVICE  
COMPONENTS SO AS TO REDUCE OR  
ELIMINATE THE OCCURENCE OF  
DELAMINATION THEREOF AND CRACKING  
THEREIN

**Confirmation No.:** 3493

**Examiner:** J. Stark

**Group Art Unit:** 2823

**Attorney Docket No.:** 2269-5565.1US  
(2002-1124.01/US)

VIA ELECTRONIC FILING  
March 28, 2008

**RESPONSE TO FINAL OFFICE ACTION**

Mail Stop AF  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Examiner:

This Response follows the final Office Action of January 28, 2008, the shortened statutory period for response to which expires on April 28, 2008. This response is being submitted within two months of the mailing date of the final Office Action.